

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 2002-062226

(43)Date of publication of application : 28.02.2002

(51)Int.Cl.

G01N 1/28
 G01N 1/00
 G01N 1/32
 H01J 37/20
 H01J 37/30
 H01J 37/317

(21)Application number : 2000-248030

(71)Applicant : JEOL LTD

(22)Date of filing : 18.08.2000

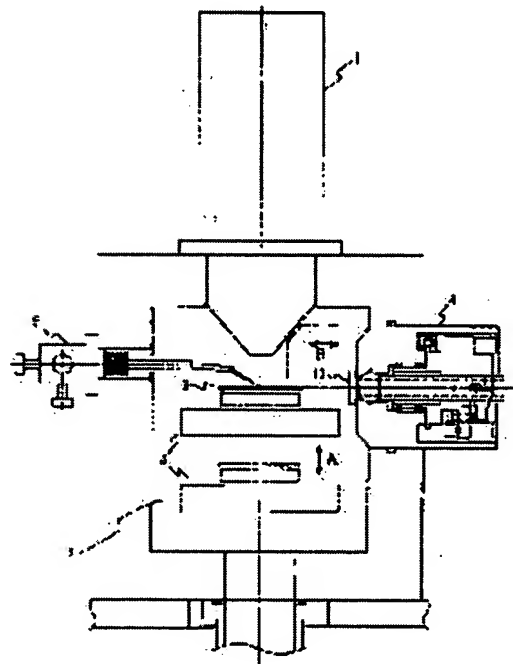
(72)Inventor : KASAI TORU

(54) SAMPLE PREPARING DEVICE FOR FIB SAMPLE

(57)Abstract:

PROBLEM TO BE SOLVED: To enhance operation, workability of sample preparation for TEM observation and to facilitate additional working.

SOLUTION: This preparation device for an FIB sample locally cuts out a observation target part of a wafer 3 with a focused ion beam, and works in a sample 12 observable with a transmission electron microscope, and has a sample stage 4 for the wafer for placing the wafer 3 and locally cutting out the observation target part; a TEM sample stage 6 for mounting the cut out sample 2 and working in the sample observable with the transmission electron microscope; and a manipulator 5 for gripping out the sample cut out with the sample stage 4 for the wafer and fixing it to the TEM sample stage 6, within an FIB sample chamber 2. The sample stage 4 for the wafer and the TEM sample stage 6 have a moving mechanism movable to the FIB working position without interference of mutual staged.



LEGAL STATUS

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]

Copyright (C); 1998,2003 Japan Patent Office